

WHAT IS CLAIMED IS:

1. A method for discharging an in-plane switching mode liquid crystal display panel, comprising:

providing a color filter substrate and a thin film transistor substrate;

forming a liquid crystal layer between the color filter and thin film transistor substrates to form a liquid crystal display panel; and

discharging at least one surface of the liquid crystal display panel using an ionizer system.
2. The method of claim 1, wherein the discharged surface is on the thin film transistor substrate.
3. The method of claim 1, wherein the discharged surface is on the color filter substrate.
4. The method of claim 1, wherein both the thin film transistor substrate and the color filter substrate are discharged during the step of discharging.
5. The method of claim 1, further comprising performing a lighting test of the liquid crystal display panel.

6. A method for discharging an in-plane switching mode liquid crystal display panel, comprising:

forming a color filter substrate and a thin film transistor substrate;

forming a liquid crystal layer between the color filter and thin film transistor substrates to form a liquid crystal display panel;

discharging the thin film transistor substrate of the liquid crystal display panel;

and

performing a lighting test for the liquid crystal display panel.

7. The method of claim 6, wherein the discharging of the thin film transistor is performed using an ionizer system.

8. A method for discharging an in-plane switching mode liquid crystal display panel, comprising:

forming a color filter substrate and a thin film transistor substrate;

forming a liquid crystal layer between the color filter and thin film transistor substrates to form a liquid crystal display panel;

simultaneously discharging the color filter substrate and the thin film transistor substrate of the liquid crystal display panel; and

performing a lighting test for the liquid crystal display panel.

9. A method for fabricating an in-plane switching mode liquid crystal display panel, comprising:

forming a thin film transistor substrate and a color filter substrate;

forming a plurality of thin film transistors on the thin film transistor substrate;

forming a color filter on the color filter substrate;

forming an alignment layer uniformly on the thin film transistor substrate;

attaching the thin film transistor substrate to the color filter substrate; and

providing an ionizer for removing an electrostatic charge from the liquid crystal display panel.

10. The method of claim 9, wherein forming the alignment layer includes applying a thin film of polymer and performing a rubbing process.

11. The method of claim 9, wherein the thin film transistor substrate includes a thin film transistor, a pixel electrode and a common electrode.

12. The method of claim 9, wherein the ionizer is disposed at a lower portion of the thin film transistor substrate.

13. A method for fabricating an in-plane switching mode liquid crystal display panel, comprising:

- forming a thin film transistor substrate and a color filter substrate;
- forming a plurality of thin film transistors on the thin film transistor substrate;
- forming a color filter on the color filter substrate;
- attaching the thin film transistor substrate to the color filter substrate to form a liquid crystal display panel; and
- injecting a liquid crystal into an opening of the liquid crystal display panel.

14. The method of claim 13, further comprising removing a shorting bar formed at an outer periphery of a pad portion of the liquid crystal display panel.

15. The method of claim 13, further comprising:

- disposing serially a cleaning unit and a lighting test unit; and
- providing a discharging device at each of the cleaning unit and the lighting test unit for removing an electrostatic charge from a back surface of the thin film transistor substrate.

16. The method of claim 15, wherein a discharging direction of the discharging device is oriented from an upper direction to a lower direction.

17. The method of claim 13, further comprising supplying continuously positive ions and negative ions in equal amounts through a plurality of probes to the thin film transistor substrate.

18. The method of claim 17, wherein the negative ions are (N_2^-) and the positive ions are (N_2^+).